



82963MGB
Customer No. 01333

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

John Border, et al

TECHNIQUE FOR MAKING DEEP
MICROSTRUCTURES IN
PHOTORESIST

Serial No. 09/993,033

Filed 06 November 2001

Commissioner for Patents
P.O. Box 1450
Alexandria, VA. 22313-1450

Sir:

Group Art Unit: 6479

Examiner: Kripa Sagar

I hereby certify that this correspondence is being
deposited today with the United States Postal
Service as first class mail in an envelope addressed
to Commissioner For Patents, P.O. Box 1450,
Alexandria, VA 22313-1450.

Gina Marie Schmitt
Gina Marie Schmitt

September 30 2003
Date

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TC 1700

Amendment

In response to the office action mailed July 31, 2003, please amend
the above-identified application, without prejudice, as set forth below:

Amendments to the Claims are reflected in the listing of claims, which begins
on page 2 of this paper.

Remarks/Arguments begin on page 5 of this paper.